

PATENT APPLICATION No.: 10/553,470 ATTORNEY DOCKET: 60291.000041

N THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Number : 10/553,470 Confirmation No.: 8935

Applicant : Ralf LERNER Filed : May 19, 2006

Title : MONITORING THE REDUCTION IN THICKNESS AS

MATERIAL IS REMOVED FROM A WAFER COMPOSITE AND

TEST STRUCTURE FOR MONITORING REMOVAL OF

MATERIAL

TC/Art Unit : 2812

Examiner: : Unassigned

Docket No. : 60291.000041

Customer No. : **21967**

MAIL STOP AMENDMENT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

In accordance with 37 C.F.R. §§ 1.97 and 1.98, and in compliance with the duty of disclosure set forth in 37 C.F.R. § 1.56, applicants submit attached Form PTO-SB/08B (modified) for consideration and request the references cited therein be made of record by the U.S. Patent and Trademark Office in the above-captioned application.

Applicants respectfully point out that the submission of the listed references in this Information Disclosure Statement is not an admission that they are prior art or that they are material to patentability of any claims of the application. Also, the submission of this Information Disclosure Statement is not an indication that a search has been made by Applicants.

For the convenience of the Examiner in considering the cited references, a copy of each of the cited references is enclosed with this communication. In considering the cited references, it may be noted by the Examiner that certain of the references may contain markings, underlinings, and/or other notations. These markings, underlinings, and/or other notations are not to be construed as drawing the Examiner's attention either to selected parts or away from other

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parts of the cited references. Any such markings were either present on the copies of the cited references obtained by the associated individuals, or were made thereon during the study of the references by the associated individuals.

As this application was filed after June 30, 2003, copies of U.S. patents and/or U.S. patent application publications for national stage applications under 35 U.S.C. 371 cited on the attached Form PTO-SB/08B (modified), are not being provided as specified in 1276 O.G. 55 (5 August 2003).

Consideration of the foregoing plus the prompt return of a copy of the enclosed Form SB/08B with the Examiner's initials in the left column in accordance with MPEP 609 are respectfully requested.

In accordance with 37 C.F.R. § 1.97(b), this Information Disclosure Statement is believed to be submitted prior to issuance of a first Office Action. Therefore, it is respectfully submitted that no fee is required for consideration of this information. However, in the event any fee is deemed necessary, the Commissioner is authorized to charge the undersigned's Deposit Account No. 50-0206.

Respectfully submitted,

Ce Li

HUNTON & WILLIAMS LLP

Dated:

By:

Registration No. L0214

Hunton & Williams LLP Intellectual Property Department 1900 K Street, N.W. Suite 1200 Washington, DC 20006 (202) 955-1500 (telephone) (202) 778-2201 (facsimile) CCL/asc



Substitute for form 1449A/PTO

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Application Number	10/553,470			
Filing Date	May 19, 2006			
First Named Inventor	Ralf LERNER			
Art Unit	2812			
Examiner Name	Unassigned			
Attorney Docket Number	60291.000041	<u>-</u>		

U.S. PATENT DOCUMENTS Pages, Columns, Lines, *Examiner DOCUMENT NUMBER Publication Date Name of Patentee or Where Relevant Passages or Initials No. Number - Kind Code (if known) MM-DD-YYYY Applicant of Cited Document Relevant Figures Appear 1. US-5,972,787 10-26-1999 Boggs, et al. 2. US-6,156,621 12-05-2000 Nance, et al. 3. US-6,242,320 06-05-2001 So 4. US-6,514,858 02-04-2003 Hause, et al. 5. US-6,515,826 02-04-2003 Hsiao, et al. US-US-US-US-US-US-US-US-US-US-US-US-US-US-US-US-US-US-**EXAMINER SIGNATURE DATE CONSIDERED**

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Substitute for form 1449/PTO			Application Number		10/553,470						
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	7.	\neg	JP	03-076221	04-02-1991		Sato				
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			Filing Date	May 19, 2006							
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*Examiner Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published				LATION NO					
	9. Hartmannsgruber, et al., "A Selective CMP Process for Stacked low- ★ CVD Oxide F Microelectronic Enginerring, Vol. 50, pg. 53-58, 2000.										
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